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## Study of Ejector System for cw High Power Chemical Lasers Operating

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**Key Words :** Chemical Lasers( ), High Power( ), Ejector( )

### Abstract

An in-house supersonic ejector was designed to ensure low pressure and high speed scavenging of resonating cavity of chemical lasers. For given primary flow condition, 100g/s secondary mass flow rate was observed at the design pressure. Performance validation of a supersonic ejector system along with an investigation of effects of supersonic diffuser was conducted. Placement of diffuser at the secondary inlet further reduced diffuser upstream pressure to 1/4-1/5 relieving the local to the primary supply unit. In order to increase the secondary flow, we put two ejectors capable of removing 50g/s each of secondary flows together to deal with higher mass flow. Test of the parallel unit demonstrated the secondary flow rate was proportional to the numbers of individual units that were brought together. Additionally, flow calculations with a commercial code were carried out in every case of experiment and compared with results.

$A_p/A_p^*$	:		$p$	:	
$\alpha$	:		$s$	:	
$\dot{m}_p$	:		$2$	:	
$P_p$	:		$0$	:	
$P_{0p}$	:				
$M_p$	:				1.
$\dot{m}_s$	:				
$P_s$	:				
$P_{0s}$	:		1.1		
$M_s$	:				
$D_2$	:				
$A_2$	:				
$(L/D)_2$	:	가		[1-2].	

가 [3-5].  
가 , 가

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(High Energy Laser Weapon System)  
(DF) ,  
(HF) , - (COIL,

Chemical Oxygen-Iodine Laser)

DF

3.8 $\mu$ m

10% 10kW  
100g/s

2

50g/s

20torr

50g/s

100g/s

1.2

가

가

가

[6].

가

[7-8].

2. 100g/s

2.1

가

[7-8]

100g/s

50torr

1

[9].

1

3-5

20torr

HF/DF

2

1

3

가

20torr

가

30bar

11m<sup>3</sup>

가

2.2

가

가

가

( )

가

가

2

**Table 1** Characteristics of the chemical laser gas mixture in resonator cavity

Laser	Temp. (K)	$\gamma$	$P_s$ (torr)
HF/DF	1400-1900	1.5	15-20
COIL	300-400	1.5	5-7

**Table 2** Lasing power according to secondary mass flow rate and lasing efficiency

Secondary mass flow rate	Lasing efficiency		
	5%	10%	15%
50g/s	2.5kW	5kW	7.5kW
100g/s	5kW	10kW	15kW

**Table 3** Specification of 100g/s ejector

Geometric parameters	$A_p/A_p^*$	$\alpha$	$A_2$	$(L/D)_2$
Specification	15	4°	160%	8

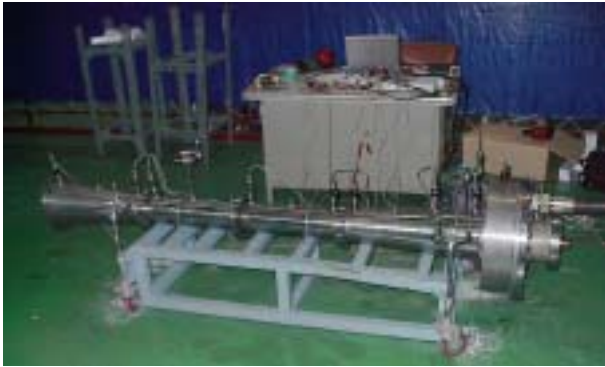


Fig. 1 100g/s single ejector

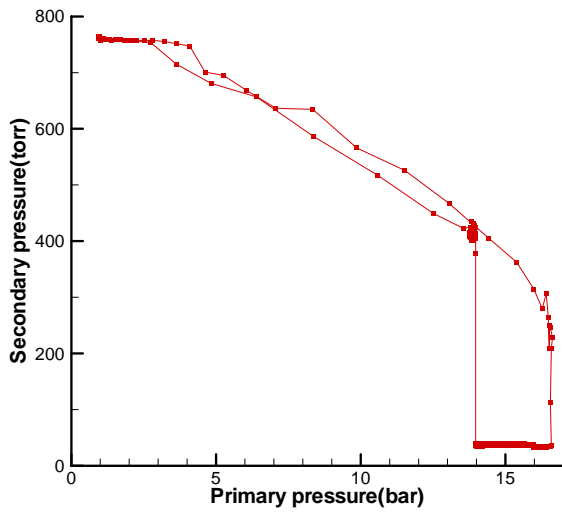


Fig. 2 Ejector performance contour

50torr  
3  
4  
가  
5 가  
가  
3.  
3.1  
. 50g/s



Fig. 3 Pressure contour of ejector

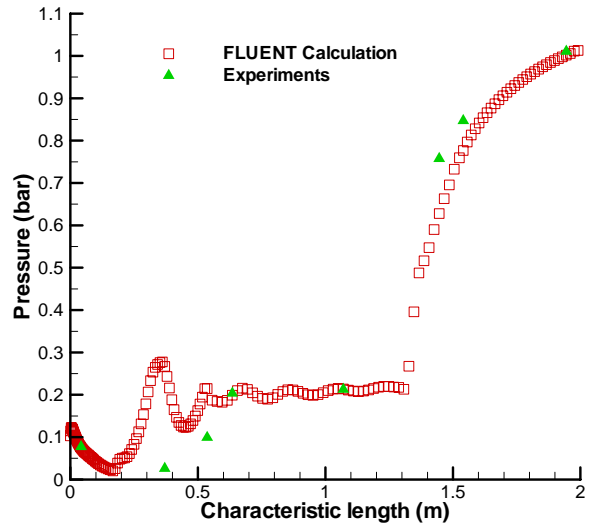


Fig. 4 Pressure distribution along the inner wall of the ejector

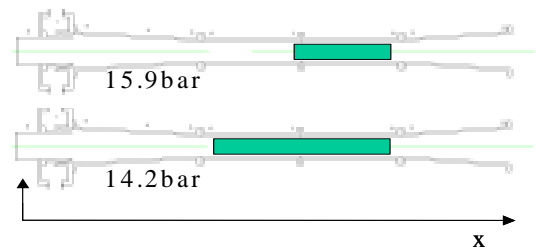
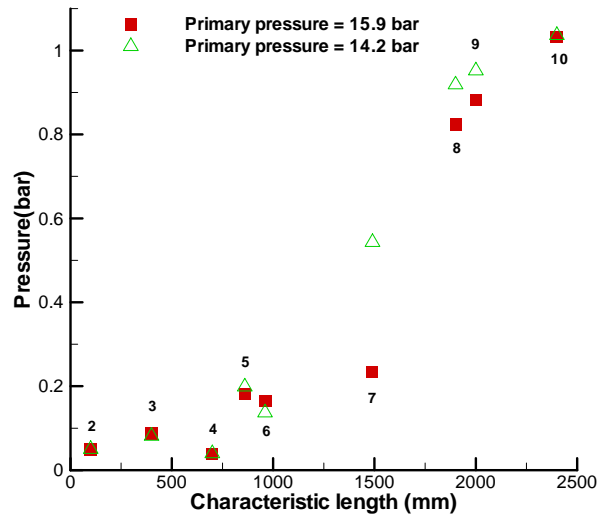
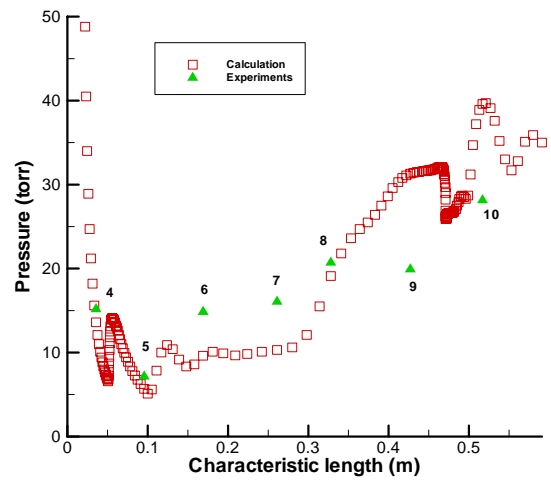


Fig. 5 Strong shock location

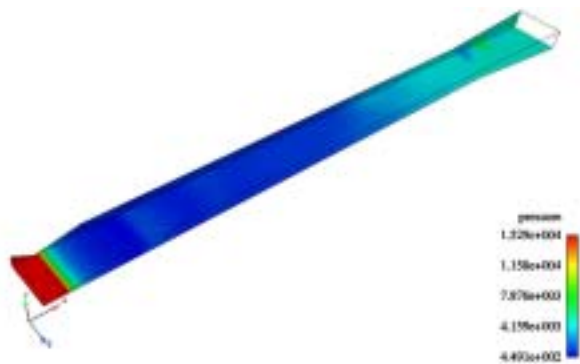
가 , 100g/s  
 가  
 3.2 가  
 가 100g/s 가  
 7 8  
 10torr  
 가



**Fig. 8** Pressure distribution along the inner wall of the diffuser with single ejector



**Fig. 6** Assembling supersonic diffuser

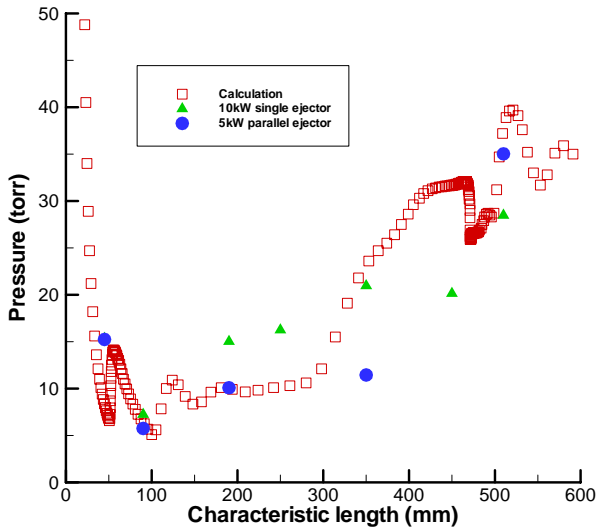


**Fig. 7** Pressure contour of diffuser

4.  
 4.1  
 가  
 가  
 가  
 가  
 가 9  
 50g/s



**Fig. 9** Parallel ejector system



**Fig. 10** Pressure distribution along the inner wall of the diffuser with parallel ejector system

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4.2 가  
 50g/s 가 10 100g/s  
 5.  
 100g/s 가  
 20torr  
 가 가 가  
 가